



Attorney Docket No. 54008.8064.US01  
P00-0021

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Eric J. BERGMAN  
APPLICATION NO.: 09/621,028  
FILED: JULY 21, 2000  
FOR: **PROCESS AND APPARATUS FOR TREATING A  
WORKPIECE SUCH AS A SEMICONDUCTOR  
WAFER**

EXAMINER: Z. EL ARINI  
ART UNIT: 1746  
CONF. NO: 4066

COMMENTS ON STATEMENT OF REASONS FOR ALLOWANCE

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

The following are Applicant's comments on the Statement of Reasons for Allowance in the September 10, 2004, Notice of Allowability.

Applicant agrees with the Examiner's Statement of Reasons for Allowance in relation to claim 1, although claim 1 further describes the ozone reacting at the surface of the wafer, to process the wafer. Claims 2-34 are allowable for reasons other than, or in addition to, those listed in the Examiner's Statement of Reasons for Allowance.

Dated: Sept. 30, 2004

Respectfully submitted,

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Certificate of Mailing

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage in an envelope addressed to Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

September 30, 2004  
Date of Deposit

Debbie Gilbert  
Debbie Gilbert